

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : (To Be Assigned) Confirmation No. : (TBA)  
PCT/JP2004/009026  
First Named Inventor : Hiroshi KANNAN  
Filed : December 27, 2005  
TC/A.U. : (To Be Assigned)  
Examiner : (To Be Assigned)  
Docket No. : 010986.57272US  
Customer No. : 23911  
Title : Plasma Generation Method, Cleaning Method, and  
Substrate Processing Method

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please enter the following amendments to the specification and claims, as amended by way of Annexes to the International Preliminary Examination Report for PCT/JP2004/009026, prior to the examination of the application during the U.S. National Phase.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 22 of this paper.